

Editorial

Although sensors and MEMS devices are used for many types of applications and in various fields, the range of devices available is not great compared with semiconductor devices such as those for memory and CPUs. Therefore, researchers and engineers must work hard to develop new and high-quality devices for a wide range of different users. To achieve this, extensive efforts are required to improve the properties and modify the structure of presently available devices. However, further efforts are also required to develop new processes and to identify new materials, which are able to improve device characteristics markedly, and to produce new concepts for devices. In particular, new processes and materials have been studied in the field of semiconductor engineering. The results of such studies are also very important with respect to sensors and MEMS, for producing new devices.

Recently, sensors and networks have been combined to produce a new concept system, such as the ubiquitous computer which has a wide range of applications. The sensor industry could open up a large new market if network sensors can be established. To realize network-sensor systems, researchers from different fields should work in cooperation. In this international journal *Sensors and Materials*, to support the development of such new-concept sensors, I hope many manuscripts related to this new field will be submitted, in addition to those focusing on individual sensors and materials.

Finally, it is my great pleasure to assume the role of Editor of *Sensors and Materials*. I am grateful to the Editor-in-Chief S. Sugiyama, and the Editors, Professor J. G. Korvink, Professor M. L. Reed, and Professor K. Toko, for recommending me.

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